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In re application of : Confirmation No. 4090

Kazuto HIROKAWA et al. : Docket No. 2003_0960A

Serial No. 10/617,789 : Group Art Unit 3723

Filed July 14, 2003 : Examiner Hadi Shakeri

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AMENDMENT AFTER FINAL OFFICE ACTION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT ACCOUNT NO. 23-0975

Sir:

In response to the Office Action of June 9, 2005, the period for response to which having been extended by one month to October 9, 2005, please amend the above-identified U.S. Patent application as follows: